

Design and Performance Analysis of CNTFET Based Asymmetric Threshold *Stacked* Leakage Reduction Technique for NVSRAM Cells

Uma Maheshwar Janniekode¹, Rajendra Prasad Somineni²

¹Research Scholar, Department of ECE, VNR Vignana Jyothi Institute of Engineering and Technology, JNTU Hyderabad, Telangana, India
Email: j.umamahesh21[at]gmail.com

²Professor, Department of ECE, VNR Vignana Jyothi Institute of Engineering and Technology, JNTU Hyderabad, Telangana, India
Email: rajendraprasad_s[at]vnrvjiuet.in

Abstract: *The Asymmetric Threshold and Stacking (AT-S) technique has already proved effective for leakage mitigation in CMOS memories. In this work we extend and quantify its impact on Carbon Nanotube Field-Effect Transistor (CNTFET) implementations of Non-Volatile SRAM (NVSRAM), including a recently reported 8T3R NVSRAM cell. Standard 6T/8T NVSRAMs and the 8T3R architecture were modelled in a 16 nm CNTFET process and benchmarked, under identical bias and workload conditions, against functionally equivalent 16 nm CMOS designs. All circuits were simulated with Synopsys HSPICE. Applying AT-S to CNTFET NVSRAMs yielded up to 69 % average leakage-power reduction and a 60 % drop for the high-performance 8T3R cell, while preserving read/write delay and static noise margin. Relative to their CMOS counterparts, CNTFET-based AT-S cells delivered an additional ≈10 % leakage saving and superior process-voltage-temperature robustness. These results demonstrate that (i) the AT-S technique remains highly effective when ported from CMOS to emerging CNTFET technology, and (ii) CNTFET devices further amplify the power-efficiency gains, making the combined solution a compelling candidate for next-generation low-power, high-speed non-volatile memories.*

Keywords: CMOS, SRAM, NVSRAM NVM, CNTFET, HSPICE, ReRAM

1. Introduction

Complementary Metal-Oxide Semiconductor (CMOS) technology has long been the foundation of digital electronics due to its scalability and cost-effectiveness. However, scaling CMOS below the 20 nm node introduces challenges like increased leakage power, short-channel effects, process variability, and performance degradation [1], [2]. To overcome these issues, Carbon Nanotube Field-Effect Transistors (CNTFETs) have emerged as a promising alternative. CNTFETs provide near-ballistic transport, high carrier mobility, low subthreshold swing, and superior electrostatic control, making them ideal for low-power, high-performance applications, particularly in nanoscale memory design [3], [4].

Conventional Static Random-Access Memory (SRAM) is fast and power-efficient but suffers from volatility and high leakage in standby mode, especially at smaller technology nodes [5]. These drawbacks have increased interest in Non-Volatile SRAM (NVSRAM), which combines a traditional SRAM core with non-volatile elements. NVSRAM offers instant-on capability, data retention during power-off, and improved power efficiency for energy-limited applications like IoT, biomedical devices, and edge computing [6].

Several non-volatile memory (NVM) technologies have been explored for NVSRAM integration, including Flash, FeRAM, MRAM, Phase-Change Memory (PCM), and Resistive RAM (ReRAM) [7]. ReRAM stands out due to its simple structure, CMOS compatibility, fast switching, low voltage operation, and excellent scalability [8], [9]. ReRAM-based NVSRAM uses materials like HfO₂ and TiO₂ for resistive switching, enabling data retention. While ReRAM-CMOS integration

has been widely studied, combining ReRAM with CNTFETs offers even greater benefits. CNTFET-based NVSRAMs with ReRAM achieve reduced leakage, improved energy efficiency, and faster read/write speeds, all while supporting high integration density [10], [11].

This study adapts the Asymmetric Threshold and Stacking (AT-S) technique, originally used for leakage reduction in CMOS NVSRAM—for CNTFET-based NVSRAMs, including the 8T3R architecture. We evaluate ReRAM integration in both CMOS and CNTFET-based NVSRAM cells. Simulations at the 16 nm node using Synopsys HSPICE assess leakage power, performance, and stability. Results show that the CNTFET + ReRAM + AT-S combination delivers superior energy efficiency and performance, confirming its potential for future ultra-low-power memory applications

2. Emerging Technologies

a) Resistive Random Access Memory (ReRAM)

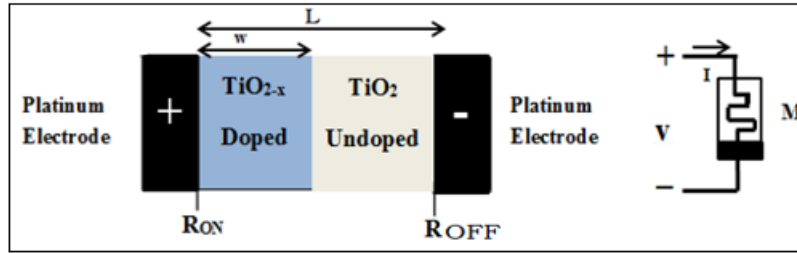
Resistive Random Access Memory (ReRAM) is a non-volatile memory technology that operates by changing the resistance of a metal-oxide layer. Its origin is rooted in the memristor concept introduced by Leon Chua in 1971, defined as a two-terminal device that maintains a functional relationship between electric charge q and magnetic flux ϕ [12] as shown in Fig. 1.

The device stores information by altering its memristance M , which governs its current-voltage behavior as:

$$i(t) = X_m^{-1} \cdot v(t)$$

where X_m is the internal state variable representing the memristance.

Figure 1 Memristor structure and its circuit symbol in which thick lines represent doped layer



A practical model views the memristor as two resistors in series: R_{ON} (low resistance) and R_{OFF} (high resistance), with a boundary w determining the active region. The equivalent resistance is:

$$R(w) = R_{ON} \times \frac{w}{L} + R_{OFF} \left(1 - \frac{w}{L}\right) \quad (1)$$

The memristance as a function of charge $q(t)$ is modelled as:

$$M(q) = R_{OFF} \left(1 - \frac{\mu_V R_{ON} q(t)}{L^2}\right) \quad (2)$$

where: μ_V : mobility of oxygen ions, L : total device length.

The I-V relationship becomes:

$$V(t) = \left(R_{ON} \times \frac{w(t)}{L} + R_{OFF} \left(1 - \frac{w(t)}{L}\right)\right) i(t) \quad (3)$$

with $w(t)$ evolving as:

$$w(t) = \frac{\mu_V R_{ON}}{L} q(t) \quad (4)$$

This switching is based on the drift of oxygen vacancies forming or rupturing a conductive filament in the oxide layer (e.g., TiO_2), toggling between LRS and HRS [13][14].

b) Carbon Nanotube Field-Effect Transistor (CNTFET)

As silicon-based CMOS technology nears its physical and scaling limits, emerging nanotechnologies are being explored for future VLSI systems. Among them, Carbon Nanotube Field-Effect Transistors (CNTFETs) stand out due to their superior electrical, mechanical, and thermal properties. CNTFETs utilize semiconducting single-walled carbon nanotubes (SWCNTs) as channel material, replacing silicon. Their quasi-one-dimensional structure enables near-ballistic transport, high carrier mobility, and steep subthreshold

slopes, resulting in high-speed, low-power, and high-density nano electronic circuits.

With configurable chirality vectors (n, m) that define their bandgap, CNTFETs offer better control over switching behaviour. They also exhibit reduced leakage current and are less affected by short-channel effects than traditional MOSFETs, making them ideal for nanoscale logic and memory applications [15][16]. Figure 2 depicts the structure of carbon nanotubes, which are cylindrical in shape and possess unique physical and electrical traits.

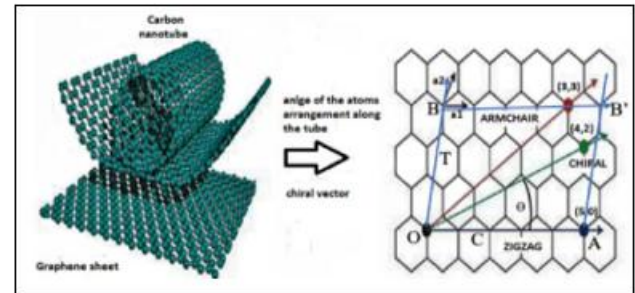


Figure 2: Rolling Graphene sheet to create Carbon Nanotube

c) Design Parameters of CNTFETs

To accurately model and design CNTFET-based circuits, several device-level parameters must be considered. These include chirality, diameter, channel length, threshold voltage, and capacitances. The Table 1 summarizes key parameters along with their governing equations. CNTFETs are often considered for integration with emerging memories like ReRAM to build energy-efficient non-volatile logic and storage subsystems [17][18].

Table 1: CNTFET Design Parameters and Equations

Parameter	Typical Value	Equation / Formula	Description
Chirality (n, m)	$(19, 0)$	—	Defines the CNT structure and its semiconducting or metallic nature.
CNT Diameter d	~ 1.5 nm	$d = a \frac{\sqrt{m^2 + n^2 + mn}}{\pi}$ $= \frac{ch}{\pi} = 0.246$	Affects threshold voltage and bandgap.
Bandgap E_g	~ 0.6 eV	$E_g = \frac{2aV_{\pi}}{d} = V_{\pi} = 3\text{ eV}$	Inversely proportional to diameter.
Threshold Voltage V_{th}	$0.2-0.3$ V	$V_{th} = \frac{E_g}{2q}$	Depends on the CNT bandgap.
Channel Length L	16 nm	—	Affects short-channel effects and delay.
Gate Oxide Thickness	1.5 nm	$C_{ox} = \frac{2\pi\epsilon_{ox}L}{\ln(2h/r)}$	Affects gate control over the channel.
Quantum Capacitance C_Q	—	$C_Q = \frac{4q^2}{h\nu_F}$	Arises from 1D density of states of CNT.
Total Gate Capacitance C_g	—	$C_g = \left(\frac{1}{C_{ox}} + \frac{1}{C_Q}\right)^{-1}$	Combination of oxide and quantum capacitance.

43 of 47

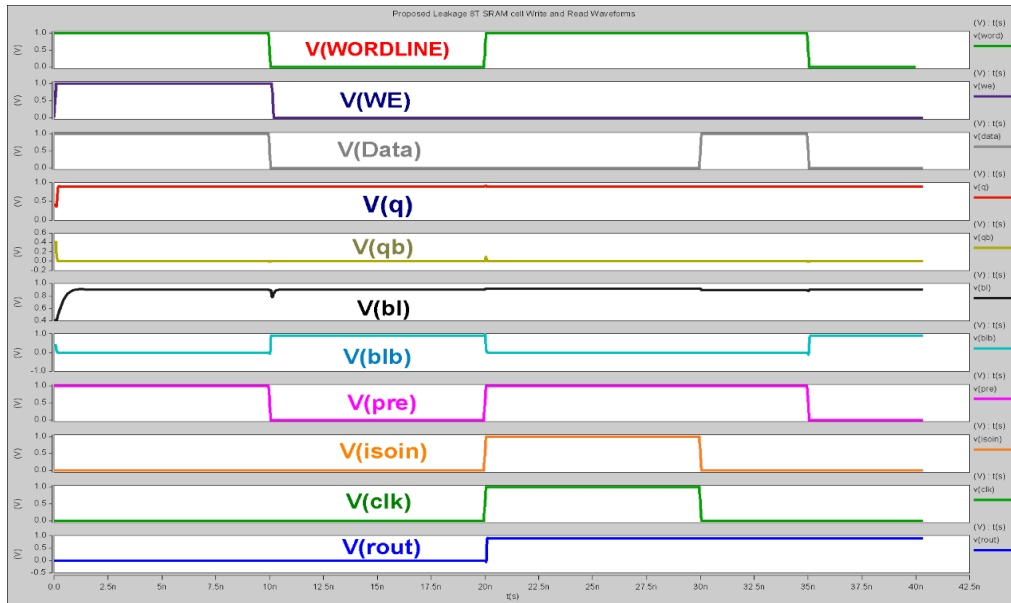


Figure 4: Read and Write Operations Waveforms of Asymmetric Threshold Stacked SRAM Cell

- c) **Extending AT-S to NVSRAM for Enhanced Leakage Reduction:** Figures 5, 6, 7, and 8 show how the AT-S SRAM cell is augmented into a Non-Volatile SRAM cell by integrating resistive memory elements (R1, R2, R3 – likely memristors or RRAM) and Leakage Reduction Technique.

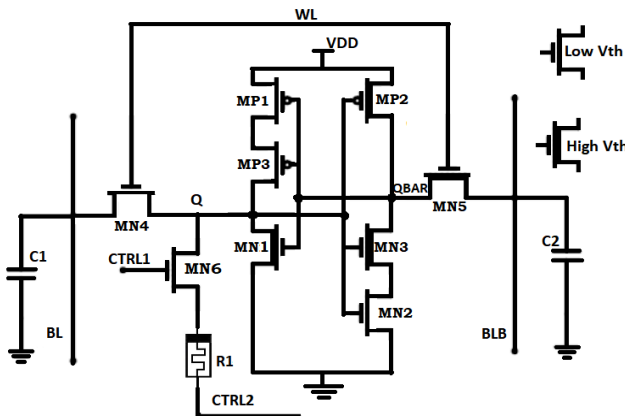


Figure 5: 7T1R NVSRAM Cell With Proposed Leakage Reduction Technique

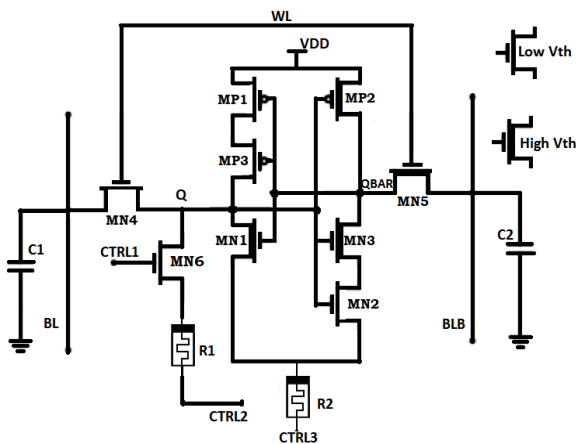


Figure 6: 7T2R NVSRAM Cell With Proposed Leakage Reduction Technique

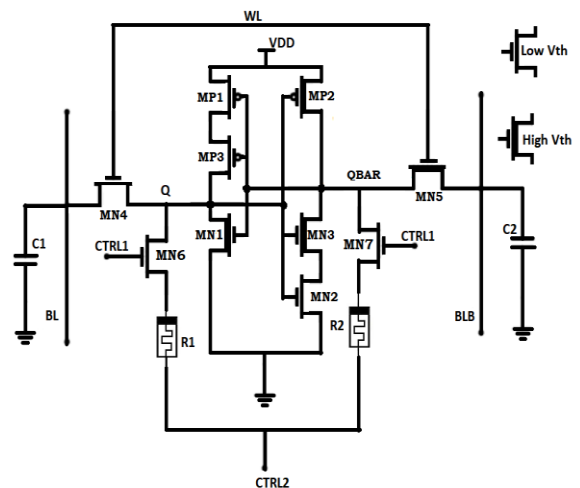


Figure 7: 8T2R NVSRAM Cell With Proposed Leakage Reduction Technique

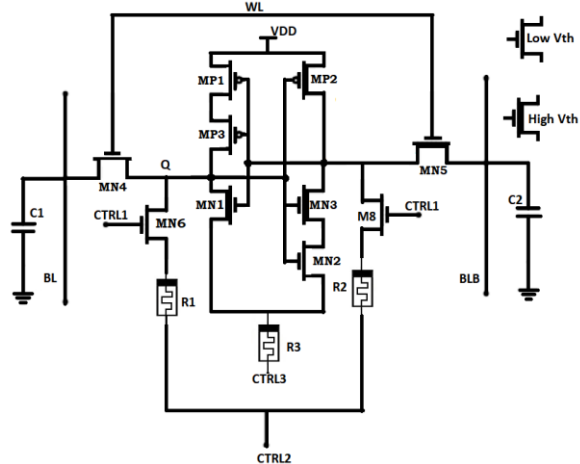


Figure 8: Proposed 8T3R NVSRAM Cell With Proposed Leakage Reduction Technique

- d) **Integration of Non-Volatile Elements:** NVSRAM cells incorporate resistive elements parallel to parts of the SRAM latch for non-volatile data storage. Data is saved from volatile SRAM nodes (Q, QBAR) to these elements before power-down and restored upon power-up [20].

Dedicated Leakage Reduction Mechanism: Beyond the intrinsic AT-S of the SRAM core, the Proposed Leakage Reduction Technique involves:

Footer Transistors (MN6, MN7): These NMOS transistors are placed between the SRAM inverters' pull-down network and ground. In the diagrams, MN6 and MN7 connect to Q/QBAR and CTRL2, effectively disconnecting the path to ground.

Control Signals (CTRL1, CTRL2, CTRL3): These signals gate MN6 and MN7. When these transistors are turned OFF (e.g., by CTRL1/CTRL2), they sever leakage paths, significantly reducing static power during standby or data retention. This acts as a cell-level power gating mechanism.

Memristor Gating: The memristors (R1, R2, R3) and their control signals (CTRL2, CTRL3) manage store/recall operations and can also power-gate the non-volatile elements to eliminate their leakage during power-off.

The 7T1R cell (7 transistors, 1 resistive element) and 7T2R cell (7 transistors, 2 resistive elements) represent different non-volatile integration densities. Dynamic power management is enabled by CTRL1, which, when low, turns off MN6 and MN7, cutting ground leakage paths.

e) E. Implementing AT-S in CNTFET NVSRAM Cells: The Next Frontier

While the figures use CMOS symbols, the AT-S concept is highly advantageous for CNTFETs.

- **Inherent Advantages of CNTFETs for AT-S:** Precise Threshold Voltage Control: CNTFET V_{th} can be finely tuned by varying the carbon nanotube's diameter and chirality, offering superior "Asymmetric Threshold" design compared to CMOS multi- V_{th} processes.
- **High Performance:** CNTFETs exhibit ballistic transport, leading to higher ON-currents and faster switching. Low- V_{th} CNTFETs can achieve superior drive strengths than CMOS, enhancing NVSRAM speed.
- **Superior Electrostatic Control and Lower Leakage:** The excellent gate control in CNTFETs results in a steeper subthreshold slope and inherently lower OFF-state currents. The "Stacked" effect further magnifies this intrinsic low leakage, drastically reducing overall power consumption.

- **Memristor Integration:** Advancements in CNT-based memristors can further enhance non-volatile capabilities and reduce power consumption during store/recall.

The entire AT-S NVSRAM circuit topology can be realized with CNTFETs, leveraging their benefits for superior power efficiency, speed, and stability, potentially overcoming CMOS scaling limits and leakage challenges.

f) Overall Benefits and Conclusion

The AT-S leakage reduction technique is a robust design methodology for advanced SRAM and NVSRAM. By combining asymmetric thresholds and stacked configurations, it effectively tackles static power dissipation. In CMOS, AT-S offers a practical balance of performance and power. When extended to NVSRAM with dedicated leakage mechanisms, it enables highly efficient data retention and power management.

The migration of AT-S to CNTFET technology holds immense potential. CNTFETs' precise V_{th} tunability, superior electrostatic control, and inherent low leakage align perfectly with AT-S principles. This synergy could yield NVSRAM cells with dramatically reduced power consumption, higher speeds, and enhanced stability, paving the way for next-generation memory solutions. As CNTFET fabrication matures, AT-S could be a foundational design principle for ultra-low-power, highly reliable non-volatile memories.

4. Results and Discussion

The Asymmetric Threshold Stacked (AT-S) leakage reduction technique, illustrated across various NVSRAM cell designs (Figures 5-8), represents a sophisticated approach to mitigate static and dynamic power consumption. Building from an 8T SRAM core (Figure 3), the technique integrates non-volatile resistive memory elements and dedicated power-gating transistors (MN6, MN7) controlled by external signals (CTRL1, CTRL2, CTRL3). The core AT-S principle involves judiciously assigning different threshold voltages to transistors—high V_{th} for lower leakage in standby paths and low V_{th} for faster switching in active paths—and stacking transistors in series to exploit the "stack effect," thereby significantly reducing subthreshold leakage.

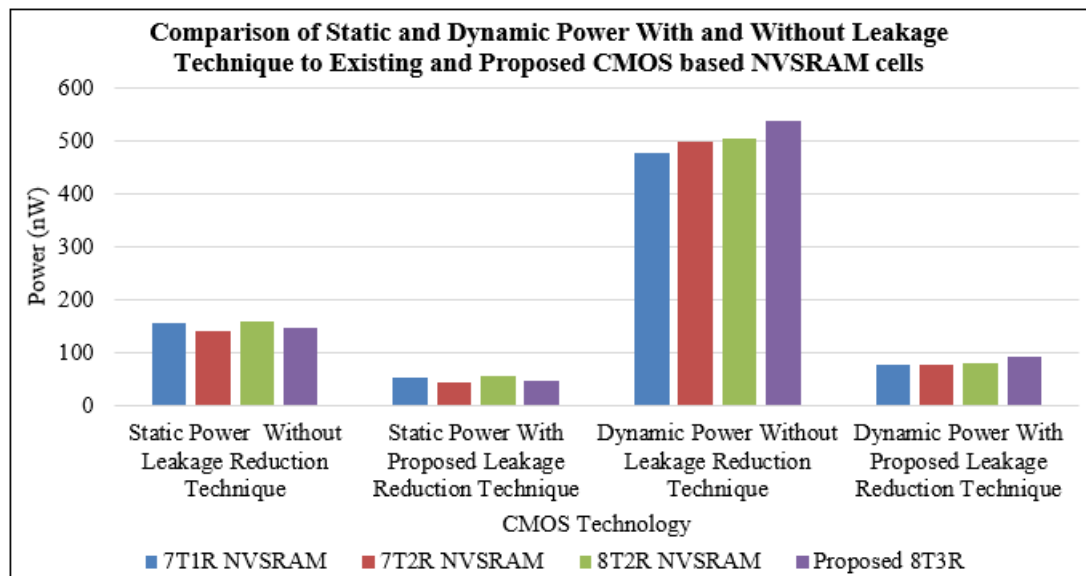


Figure 9: Comparison of Static and Dynamic Power with and without Leakage Technique to Existing and Proposed CMOS based NVSRAM cells Techniques

Simulation results for both CMOS (Figure 9) and CNTFET (Figure 10) implementations strongly validate the efficacy of this technique. In CMOS NVSRAM cells, the AT-S method dramatically cuts static power by over 60%, reducing consumption from approximately 140-155 nW to a mere 40-50 nW. A substantial reduction in dynamic power (from ~470-540 nW down to ~70-90 nW) is also observed, highlighting

the technique's benefits during active operation. Furthermore, when applied to CNTFET-based NVSRAM, which inherently boasts lower power due to superior electrostatic control and tunable threshold voltages, the AT-S technique achieves even more impressive results. Static power drops from an already low 25-45 nW to an ultra-low 8-15 nW, and dynamic power decreases from 230-270 nW to 55-65 nW.

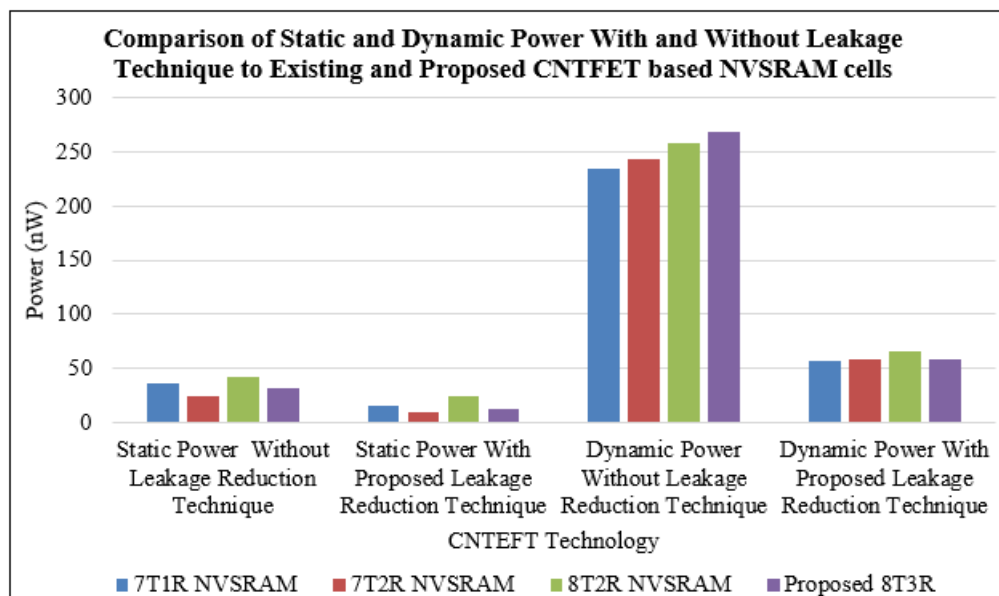


Figure 10: Comparison of Static and Dynamic powers of existing and Proposed Leakage Reduction Techniques

This powerful synergy between the AT-S circuit design and the intrinsic advantages of CNTFET technology underscores its potential for future memory solutions. While slightly higher power figures are noted for more complex cell designs like the Proposed 8T3R variant, the overall impact of the AT-S technique remains profoundly positive. It positions CNTFETs as a leading contender for developing ultra-low-power, high-performance, and highly reliable non-volatile memories, effectively addressing critical power efficiency challenges in advanced electronic systems.

4. Conclusion

This work investigates the design and optimization of NVSRAM cells using CNTFET technology, focusing on minimizing leakage power through the Asymmetric Threshold and Stacking (AT-S) technique. Simulation results show that the AT-S approach achieves up to 69% leakage reduction, significantly enhancing the power efficiency of both conventional and advanced 8T3R NVSRAM designs. The adoption of 16nm CNTFET technology further reinforces the compatibility of the proposed method with modern semiconductor scaling trends. The consistent performance

improvements across multiple NVSRAM configurations underscore the robustness and scalability of the AT-S technique. Overall, the integration of CNTFETs and advanced leakage control strategies like AT-S positions these designs as strong candidates for next-generation, low-power non-volatile memory solutions.

References

- [1] J. P. Colinge, *FinFETs and Other Multi-Gate Transistors*, Springer, 2008.
- [2] M. Horowitz et al., "Scaling, power, and the future of CMOS," in *Proc. IEEE IEDM*, Dec. 2005, pp. 9–15.
- [3] A. Naeemi and J. D. Meindl, "Carbon nanotube interconnects," *IEEE Trans. Electron Devices*, vol. 55, no. 10, pp. 2574–2581, Oct. 2008.
- [4] M. M. Shulaker et al., "Carbon nanotube computer," *Nature*, vol. 501, pp. 526–530, Sep. 2013.
- [5] B. Nikolić et al., "Design issues in SRAM memories," in *Proc. CICC*, 2000, pp. 321–324.
- [6] K. Kim and C. H. Kim, "A nonvolatile SRAM using resistive memory for fast and power-efficient mobile applications," *IEEE J. Solid-State Circuits*, vol. 47, no. 3, pp. 775–786, Mar. 2012.
- [7] S. Yu, "Resistive Random Access Memory (RRAM): an overview," *IEEE Solid-State Circuits Mag.*, vol. 8, no. 3, pp. 43–56, Summer 2016.
- [8] R. Waser and M. Aono, "Nanoionics-based resistive switching memories," *Nat. Mater.*, vol. 6, no. 11, pp. 833–840, Nov. 2007.
- [9] H.-S. P. Wong et al., "Metal–oxide RRAM," *Proc. IEEE*, vol. 100, no. 6, pp. 1951–1970, Jun. 2012.
- [10] M. A. Zidan, H. A. Fahmy, M. M. Hussain, and K. N. Salama, "CMOS-compatible memristor: Tutorial," *IEEE Circ. Syst. Mag.*, vol. 15, no. 1, pp. 8–23, 2015.
- [11] P. Rai, A. Islam, and S. M. Hasan, "CNTFET based hybrid NVSRAM design using memristive elements," in *Proc. IEEE ICECS*, 2018, pp. 173–176.
- [12] L. O. Chua, "Memristor—The missing circuit element," *IEEE Trans. Circuit Theory*, vol. 18, no. 5, pp. 507–519, Sep. 1971.
- [13] H.-S. P. Wong et al., "Metal–oxide RRAM," *Proc. IEEE*, vol. 100, no. 6, pp. 1951–1970, Jun. 2012.
- [14] S. Yu, "Resistive Random Access Memory (RRAM): an overview," *IEEE Solid-State Circuits Mag.*, vol. 8, no. 3, pp. 43–56, 2016.
- [15] Uma Maheshwar Janniekode, Rajendra Prasad Somineni, and C.D. Naidu. "Design and Performance Analysis of 6T SRAM Cell in Different Technologies and Nodes". *Int J Performability Eng*, 2021, 17(2): 167-177
- [16] M. M. Shulaker et al., "Carbon nanotube computer," *Nature*, vol. 501, pp. 526–530, 2013.
- [17] A. Naeemi and J. D. Meindl, "Performance comparison between carbon nanotube and copper interconnects," *IEEE Electron Device Lett.*, vol. 26, no. 2, pp. 84–86, 2005.
- [18] P. Rai and S. M. Hasan, "CNTFET-based hybrid NVSRAM using resistive memory elements," in *Proc. IEEE ICECS*, 2018, pp. 173–176.
- [19] U. M. Janniekode and R. P. Somineni, "A Stacked SRAM Cell with Asymmetric Threshold Voltage for Low Leakage Power Applications," 2023 Global

- Conference on Information Technologies and Communications (GCITC), Bangalore, India, 2023, pp. 1-5.
- [20] U. M. Janniekode and R. P. Somineni, "Performance Analysis of RRAM Based Low Power NVSRAM Cell Designs for IoT Applications," 2022 2nd International Conference on Emerging Frontiers in Electrical and Electronic Technologies (ICEFEET), Patna, India, 2022, pp. 1-6,